Next Generation Optical Sputtering Systems for High Precision Optical Coatings

Applied Multilayers LLC offers next generation optical sputtering systems for high precision optical coatings. We offer a wide range of system platforms together with turn-key processes. Our patented technology is simple, repeatable and scaleable with many system sizes available. Ideally suited for numerous applications as durable IR coatings, durable visible AR coatings, iDLC, high laser damage coatings, ophthalmics, electrochromics and solar absorbers. Also works very well for oxides, nitrides, carbides or pure metals. Our patented optical Closed Field Magnetron (CFM) sputtering technology is the most advanced optical coating technology yet devised. It takes optical coating into a new era of precision coatings with near-bulk film densification and allows productivity from pilot to full production scalability. CFM is of "cold" deposition standards. It now allows single or multilayered film coatings onto sensitive polymer substrates or plastics which other deposition technologies would consider prohibitive. See www.applied-multilayers.com for coater and application data.

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BENCHMARK 800-III® ICP Deposition and Etch System

AXIC, Inc.'s BENCHMARK 800-III® Inductively Coupled Plasma (ICP) Processing System is an affordable high-performance low temperature PECVD and DRIE plasma processing system. The BenchMark 800-III defines low temperature-low damage Plasma Enhanced Chemical Vapor Deposition (PECVD) plasma processing and Deep Reactive Ion Etch (DRIE). The system is based on a modular design starting with a universal chamber and cabinet unit with ICP etch and deposition bottom electrodes available for easy installation into the chamber unit. We are confident you will find the ease of use, variety of plasma processes, serviceability and attractive pricing of the BENCHMARK 800-III® unsurpassed by any other plasma product in the market. In the research and development of plasma processing, there has always been a great need for a highly versatile and reliable tool. With the ever-changing requirements in plasma research, the system selected must offer the widest range of process parameters and a high degree of repeatability for process verification. It also must be easily modified for new process requirements.

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Precision Edge Welded Bellows for Vapor Deposition Applications

BellowsTech, LLC edge-welded metal bellows are a reliable mechanical seal for Ultra High Vacuum (UHV) chambers. Edge welded bellows are constructed by stamping metal diaphragms with the inside and outside diameters held to tight tolerances. The inside diameters of two diaphragms are welded together. The process is continued for as many diaphragms as required by the application. Then, the welded assemblies are stacked for outside diameter welding. End pieces are added as required by the customer to create the final metal bellows assembly. Bellows mechanical seals, lifter assemblies, and feedthroughs add motion, sealing and protection to vapor deposition. Metal bellows for vapor deposition applications are typically manufactured from stainless steel or AM350. These metals can withstand ultra-high vacuums and low leak rates. Certain cleaning processes can be used on the bellows assembly before shipment to ensure that the process does not become contaminated.

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